

FORM PTO-1449
(REV. 7-80)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
136086-1SERIAL NO.
10/655,350

**SUPPLEMENTAL
INFORMATION DISCLOSURE STATEMENT BY APPLICANT
LIST OF ITEMS**

APR 04 2005

Applicant
Marc Schaepekens et al.Filing Date
9/5/03Group
1762

U.S. PATENT DOCUMENTS & U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
KMS	A1 5,846,330	12/8/98	Quirk et al.			
KMS	A2 2003/0049468	3/13/03	Hu et al.			
KMS	A3 2003/0075273	4/24/03	Kilpela et al.			
KMS	A4 2004/0040833	3/4/04	Schaepekens et al.			
	A5					
	A6					
	A7					

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
KMS	B1 EP 0 887 110	12/30/98	European			X
	B2					
	B3					

OTHER INFORMATION (Including Author, Title, Date, Pertinent Pages, etc.)

KMS	C1	PCT International Search Report dated March 14, 2005.
	C2	
	C3	
	C4	
	C5	

EXAMINER

/Kelly Stouffer/

DATE CONSIDERED

09/05/2006

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant

Form PTO-1449 US Dept. of Commerce (REV. 8-83) PATENT & TRADEMARK OFFICE				ATTY DOCKET .136086-1		APPLICATION NO.	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT Schaepkens et al.			
				FILING DATE		GROUP	

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLAS S	FILING DATE IF APPROPRI- ATE
KMS		2003/0072881	4/2003	Yang et al.			
KMS		2002/0050323	5/2002	Moisan et al.			
KMS		2001/0022295	9/2001	Hwang			
KMS		6,426,125	7/2002	Yang et al.			
KMS		6,397,776	6/2002	Yang et al.			
KMS		6,365,016	4/2002	Iacovangelo et al.			
KMS		6,213,049	4/2001	Yang			
KMS		6,110,544	8/2000	Yang et al.			
KMS		4,871,580	10/89	Schram et al.			

FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLAS S	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)			
KMS			van de Sanden et al., The expanding thermal arc plasma: the low-flow regime, Plasma Sources Sci. Technol., 7, pp. 28-35 (1998)

EXAMINER <div style="text-align: center;">/Kelly Stouffer/</div>	DATE CONSIDERED <div style="text-align: center;">09/05/2006</div>
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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
